

## **ELECTRONIC INFORMATION DISCLOSURE STATEMENT**

Electronic Version v18
Stylesheet Version v18.0

Title of ·

MODIFIED TRANSFER FUNCTION DEPOSITION BAFFLES AND HIGH DENSITY PLASMA IGNITION THEREWITH IN SEMICONDUCTOR PROCESSING

**Application Number:** 

10/080496

Confirmation Number:

8492

First Named Applicant:

Jozef Brcka

Attorney Docket Number: TAZ213

RECEIVED

Art Unit:

1763

AUG 1 5 7003

Examiner:

Luz L.

**GROUP 1700** 

Search string: ( 6287435 ).pn.

<u>Certification:</u> This Information Disclosure Statement was submitted under the following conditions, which satisfies the requirement under 37 CFR 1.97(e). The filer certified:

That each item of information contained in the information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

## **US Patent Documents**

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

2/1/05 3/21/05

init Cite.N	o. Patent No.	Date	Patentee	Kind	Class	Subclass
1	6287435	2001-09-11	Drewery et al.	7		

Signature

Examiner Name	Date
Deladio	12/23/05

ALAM 3/21/05